WHAT IS CLAIMED IS:

1. An inspection device including:

a light source;

a pellicle beamsplitter for receiving light from the light source and redirecting said light;

an aperture array for receiving light from the pellicle beamsplitter where the aperture array includes multiple arrays; and

an imaging system including an object imager including a plurality of lenses, a camera reimager including a plurality of lenses, and a camera for collecting focused light.

2. The inspection device of claim 1 wherein the multiple arrays include multiple arrays of pinholes.

3. The inspection device of claim 2 wherein the multiple arrays include multiple one dimensional arrays of pinholes.

4. The inspection device of claim 3 wherein each one dimensional array in the multiple one dimensional arrays of pinholes is conjugate to a different height from a surface to be inspected.

5. The inspection device of claim 4 wherein each one dimensional array in the multiple one dimensional arrays of pinholes is conjugate to a different height from a surface to be inspected.

6. The inspection device of claim 5 wherein the camera is one of a multi-sensor line scan camera, a multi-sensor TDI line scan camera, and a CMOS area scan camera.

7. The inspection device of claim 2 wherein the multiple arrays include multiple two dimensional arrays of pinholes.

8. The inspection device of claim 7 wherein each two dimensional array in the multiple two dimensional arrays of pinholes is conjugate to a different height from a surface to be inspected.

9. The inspection device of claim 8 wherein the camera is one of a multi-sensor line scan camera, a multi-sensor TDI line scan camera, and a CMOS area scan camera.